

37. (New) The method of claim 36 wherein the structure includes supports and wherein the formation of the ribbon in spaced relation to the electrically conductive traces creates a ribbon that is suspended from the supports.
38. (New) The method of claim 36 in which the act of selectively removing includes the act of patterning and etching the layer of nanotubes to form the ribbon.
39. (New) A method of making a circuit element comprising the acts of
providing a structure having at least one electrically conductive trace in
predefined orientation;
providing a fabric of nanotubes; and
selectively removing portions of the layer of nanotubes according to a predefined
pattern to form a ribbon having at least one nanotube such that the ribbon
crosses the electrically conductive trace but in a spaced relation thereto.
40. (New) The method of claim 39 wherein the structure includes supports and wherein the formation of the ribbon in spaced relation to the electrically conductive traces creates a ribbon that is suspended from the supports.
41. (New) The method of claim 39 in which the act of selectively removing includes the act of patterning and etching the fabric of nanotubes to form the ribbon.
42. (New) A system, comprising:
a structure having an electrically conductive trace;
a nanotube ribbon having a plurality of nanotubes in electrical contact, the ribbon
being disposed in spaced and crossed relation to the electrically
conductive trace.